Patent Application No. 10/627,611

Applicant: WATANABE et al.

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Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22314

## REPLY TO OFFICE ACTION

Sir:

In reply to the Office Action dated September 20, 2005, please enter the following amendments and consider the following remarks.

Amendments to the Title are on page 2 of this paper.

Amendments to the Specification begin on page 3 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Amendments to the Drawings begin on page 9 of this paper.

Remarks/Arguments begin on page 10 of this paper.

An **Appendix** including amended drawing figures is attached following page 12 of this paper.

## AMENDMENTS TO THE TITLE

Replace the title with:

Application No. 10/627,611

METHOD OF FABRICATING X-RAY MASK AND
METHOD OF FABRICATING SEMICONDUCTOR DEVICE
WITH USING THE X-RAY MASK FABRICATED BY THIS METHOD